



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:) Examiner: Not Yet Assigned
TAKAO YONEHARA, et al.) Group Art Unit: 2871
Application No.: 10/059,171)
Filed: January 31, 2002)
For: METHOD OF MANUFACTURING)
DISPLAY DEVICE : August 15, 2002

16 2800 MAIL ROOM
AUG 21 2002

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Commissioner for Patents
Washington, D.C. 20231

INFORMATION DISCLOSURE STATEMENT

Sir:

In compliance with the duty of disclosure under 37 C.F.R. § 1.56 and in accordance with the practice under 37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is directed to the documents listed below and on the enclosed Form PTO-1449. Copies of the below-listed documents are enclosed.

- (1) European Patent 1,122,794
- (2) European Patent 858,110
- (3) European Patent 849,788
- (4) Shimoda, T., et al., "Surface Free Technology By Laser Annealing (SUFTLA)", International Electron Devices Meeting 1999. IEDM. Technical Digest. Washington, DC, Dec. 5 to 8, 1999, New York, NY: IEEE, US, August 1, 1999 (1999-08-01), pages 289 to 292, XP000933199 ISBN: 0-7803-5411-7.
- (5) Japanese Patent 11-316397

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Assistant Commissioner for Patents, Washington, D.C. 20231 on August 15, 2002

(Date of Deposit)

Carole A. Quinn, Reg. No. 59,000

Power of Attorney for Applicant

Signature

August 15, 2002

Date of Signature

- (6) U.S. Patent 6,190,937
- (7) U.S. Patent 6,222,513
- (8) U.S. Patent 6,258,698
- (9) U.S. Patent 6,306,729
- (10) U.S. Patent 6,331,208
- (11) U.S. Patent 6,342,433
- (12) U.S. Patent 6,382,292

Documents (1) to (4) were cited during prosecution of a European counterpart application to the above-identified U.S. Application. A copy of the European Search Report, which is dated June 7, 2002, is also enclosed.

Document (5) is discussed in the subject application, commencing at page 6, line 3, and is believed to be pertinent for the reasons noted therein. Document (7) issued from U.S. Application No. 09/037,767, which is believed to be a U.S. counterpart application to JP 11-316397 (i.e., Document (5) above). An English language abstract of Document (5) is also enclosed.

The Examiner's attention is also directed to the following U.S. application, which is commonly assigned with the subject application:

<u>Application No.</u>	<u>Filing Date</u>	<u>Group Art Unit</u>
09/586,887	06/05/2000	2825

In accordance with 37 C.F.R. § 1.98(a)(2)(iii), a copy of the application, including specification, claims and drawings, is enclosed.

Finally and in an Information Disclosure Statement (IDS) filed concurrently with the subject application on January 31, 2002, the Examiner's attention was directed to two U.S. applications also filed on January 31, 2002, listed below.

<u>Application No.</u>	<u>Attorney Docket No.</u>	<u>Filing Date</u>	<u>Group Art Unit</u>
10/059,116	00862.022497	01/31/2002	2814
10/059,144	00862.022498	01/31/2002	2871

In accordance with 37 C.F.R. § 1.98(a)(2)(iii), copies of the applications, including specification, claims and drawings, were submitted with the January 31, 2002 IDS. Since these applications had not yet been assigned application serial numbers, they were identified in the January 31st IDS by their corresponding attorney docket numbers. Applicants now provide the application serial numbers and group art unit assignments corresponding to these two applications. In addition and for the Examiner's convenience, an additional copy of the specification, claims and drawings of each of these applications is provided herewith.

Inasmuch as this application has not yet received a first Office Action on the merits, it is believed that this Information Disclosure Statement is timely. See 37 C.F.R. §1.97(b)(3). Accordingly, the Examiner is urged to study this information in its entirety and to form an independent determination of the materiality of the information to the claimed invention. Additionally, the Examiner is requested to indicate that this information has been considered by initialing the appropriate portion of Form PTO-1449.

Applicants' undersigned attorney may be reached in our Costa Mesa, California office by telephone at (714) 540-8700. All correspondence should continue to be directed to our address given below.

Respectfully submitted,



Attorney for Applicants

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U.S. PATENT DOCUMENTS

*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
		6,190,937	02/20/2001	Nauagawa, et al.	438	67	
		6,222,513	03/10/1998	Howard, et al.	345	84	
		6,258,698	07/10/2001	Iwasaki, et al.	438	455	
		6,306,729	10/23/2001	Sauaguchi, et al.	438	458	
		6,331,208	12/18/2001	Nishida, et al.	117	89	
		6,342,433	01/29/2002	Ohmi, et al.	438	455	
		6,382,292	05/07/2002	Ohmi, et al.	156	584	

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT
	EP	1 122 794	08/08/2001	Europe			
	EP	858 110	08/12/1998	Europe			
	EP	849 788	06/24/1998	Europe			
	JP	11-316397	11/16/1999	Japan	G02F		Abstract

OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)

		Shimoda, T., et al: "Surface Free Technology By Laser Annealing (SUFTLA)" International Electron Devices Meeting 1999. IEDM. Technical Digest. Washington, DC, Dec. 5-8, 1999, New York, NY: IEEE, US, Aug. 1, 1999 (1999-08-01), pages 289-292, XP000933199 ISBN: 0-7803-5411-7.

EXAMINER

DATE CONSIDERED

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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